

# Full Wafer Test: Making Test More Cost-Effective

2005 SouthWest Test Workshop

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# Agenda

- **Trends in multi-up probing**
  - Total Test Time
  - Cost of Test
- **Converging Technologies**
  - Massively Parallel Test
  - Full Wafer Contact
  - Design For Test (DFT)
- **Results of technology convergence**
- **Conclusions**

# Trends in Multi-Up Probing

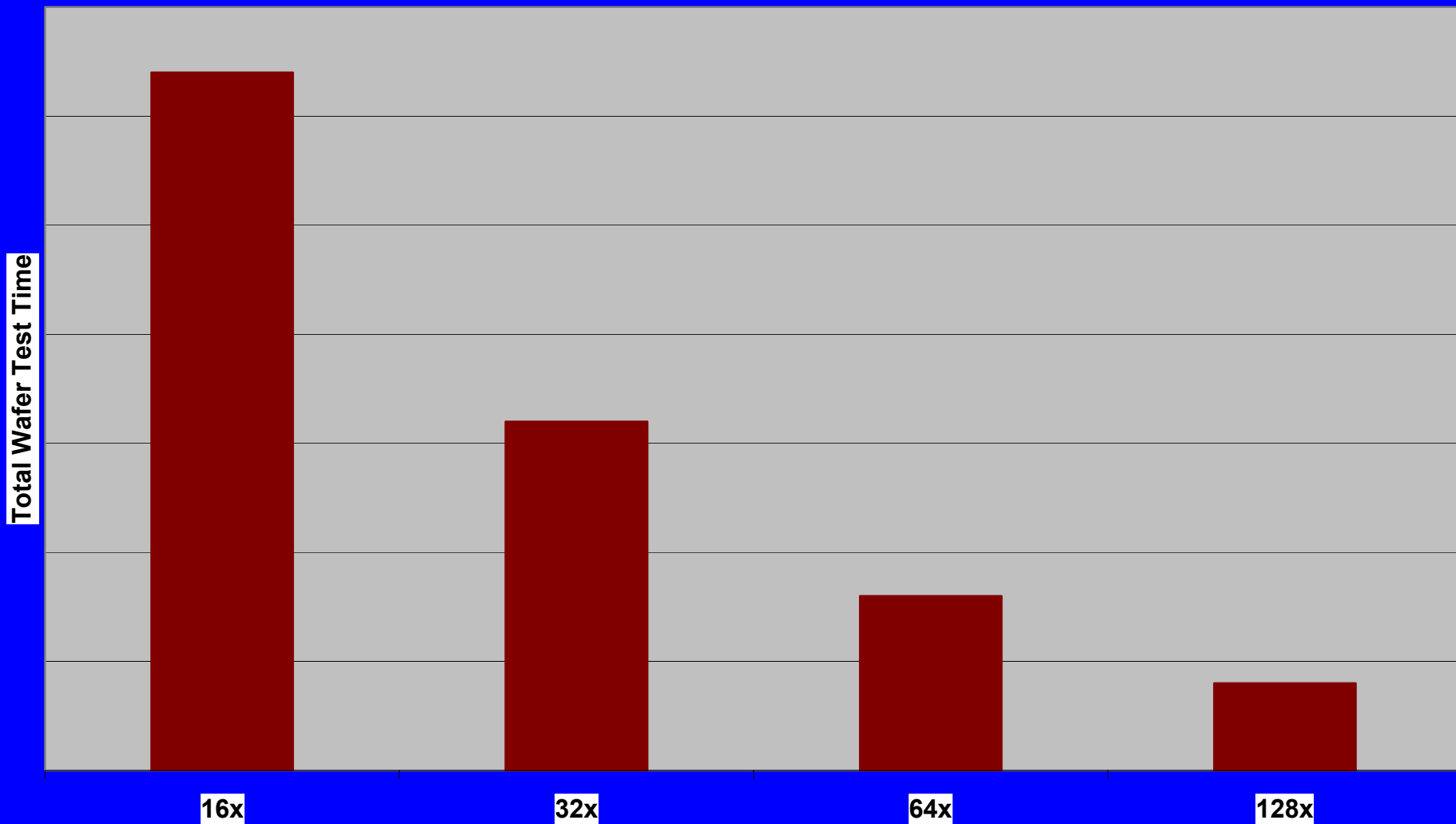
- Trend over time has been to increase the number of DUTs tested per touchdown
- Leading edge probe cards are in the range of:
  - 32 to 250 DUTs \*
  - 1000 to 5000 contacts \*
- Goal is to move closer to single touchdown testing

\* Source: “Leading Edge” of Wafer Level Testing, Bill Mann, SWTW 2004

# Total Test Time

- **Total time to test a wafer is:**
  - **Wafer exchange time (usually not significant)**
  - **Per step time \* number of steps**
    - Step time
    - Test time per step
- **What if test time per step gets long?**

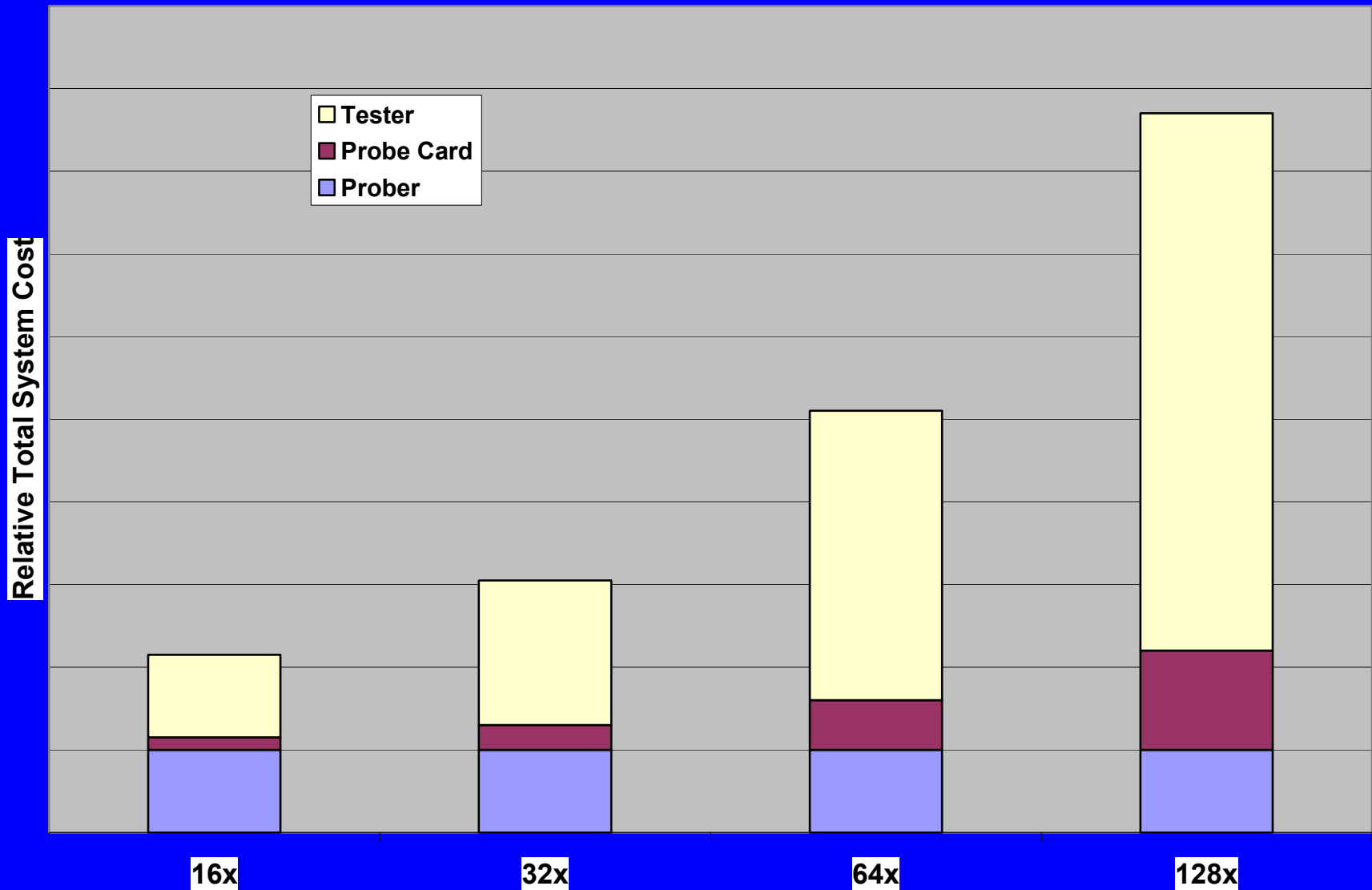
# Wafer Test Time



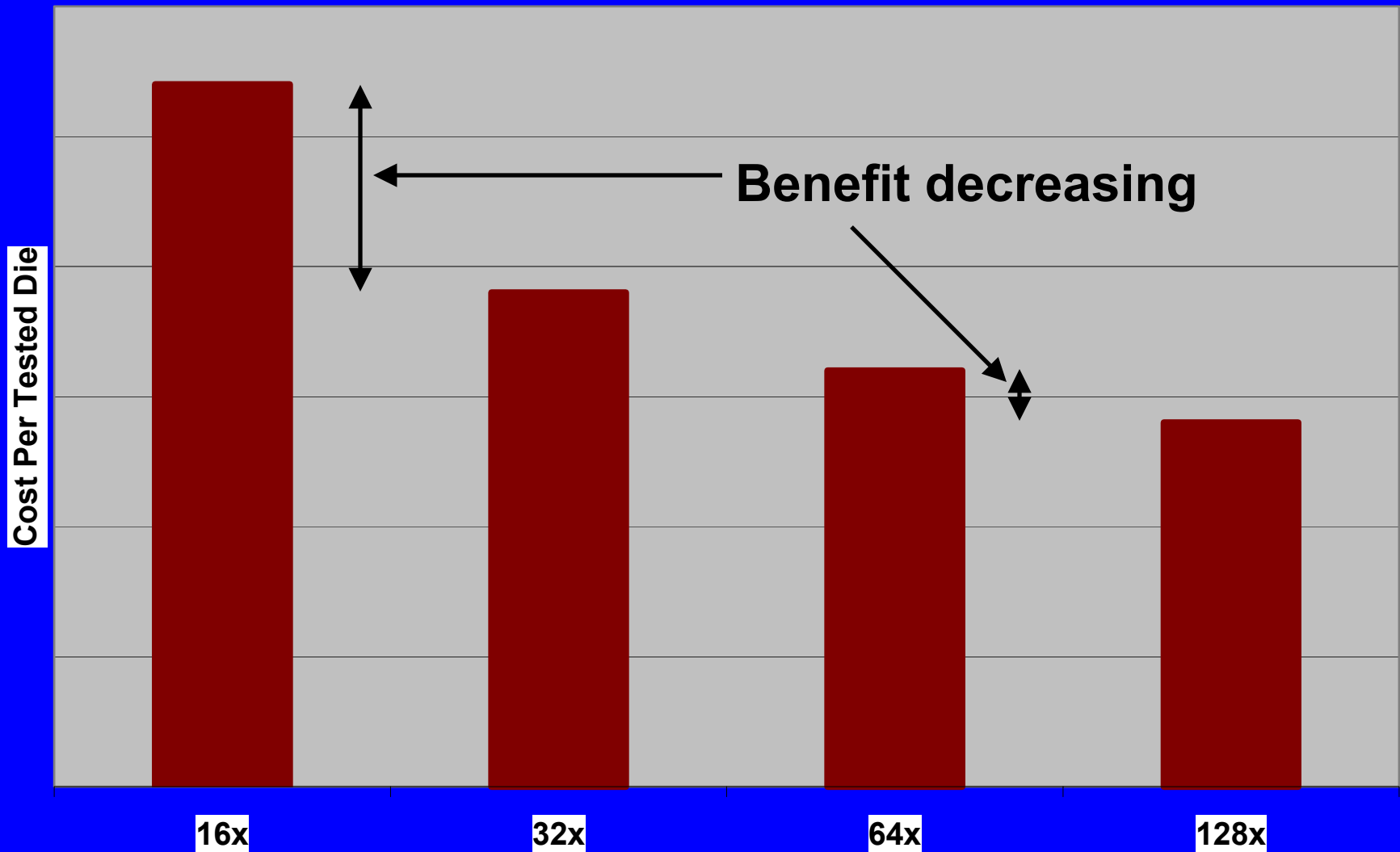
# Cost of Test

- **The primary costs are:**
  - Prober
  - Probe Card
  - Tester
- **As the number of die probed per step increases, the cost of**
  - Prober remains mostly the same
  - Probe card gets more expensive (~linear)
  - Tester gets more expensive (~linear)
- **Benefit of doubling the number of DUTs per touchdown decreases**

# Cost of Test



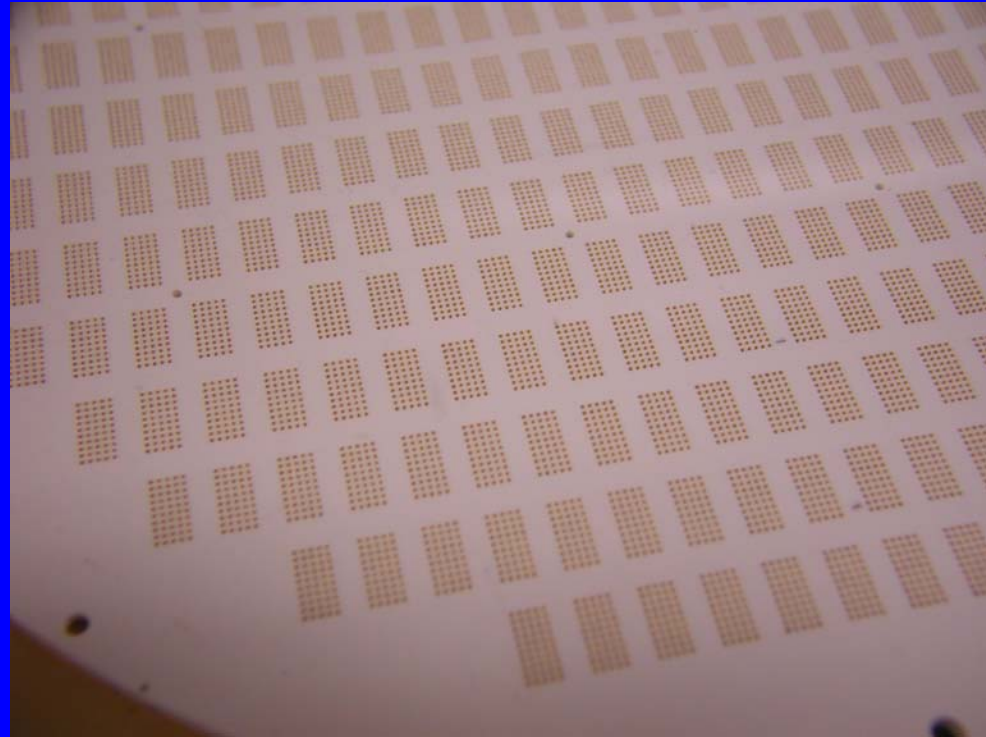
# Cost Per Tested Die



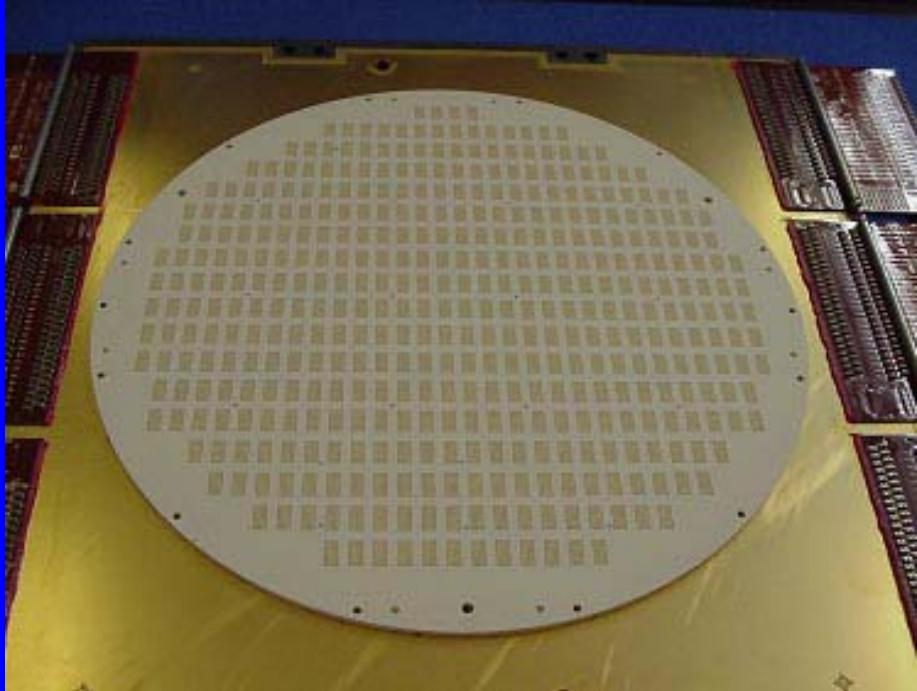


# Converging Technologies

- **Full Wafer Contact**
- **Massively Parallel Test**
- **Design For Test**



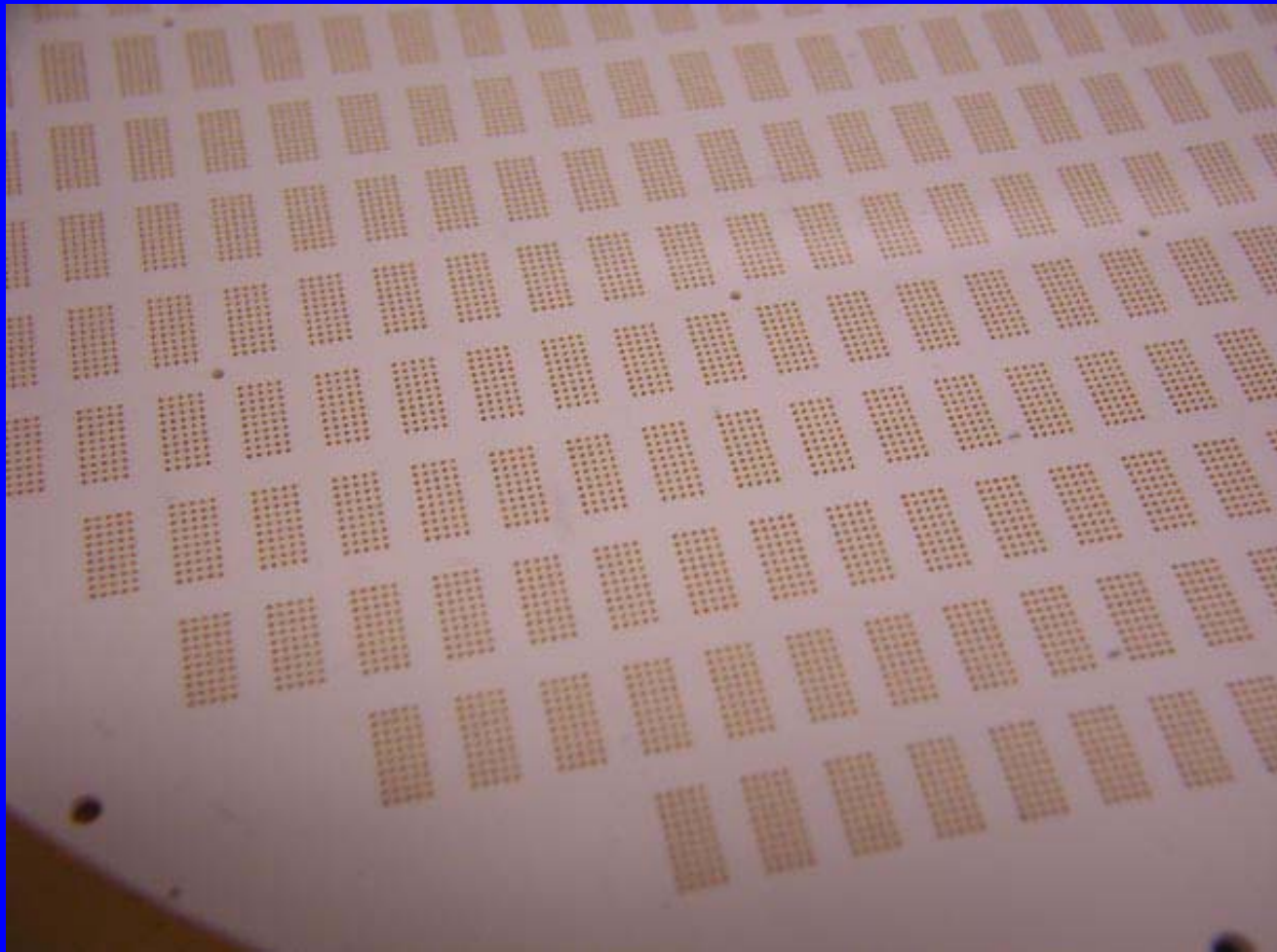
# Micro Spring Contactor



- High touchdown life
- High compliance
- Works with most pad metallurgies
- Multiple pitches available

Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

# Micro Spring Close-up (750u Pitch)



Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

6/7/2005

Steps -- Full Wafer Test

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# Full Wafer Contactor



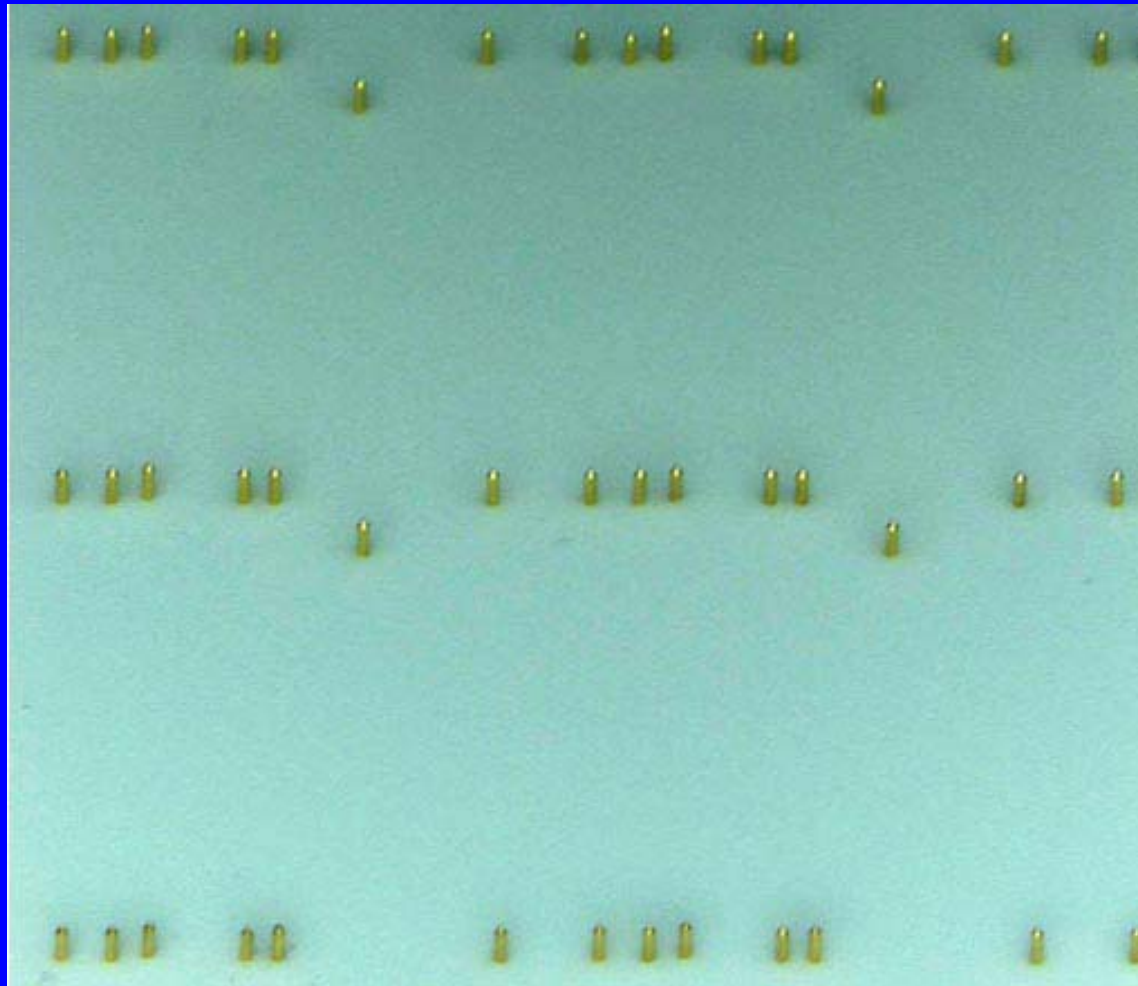
Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

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Steps -- Full Wafer Test

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# Micro Spring Close-up (200u Pitch)



Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

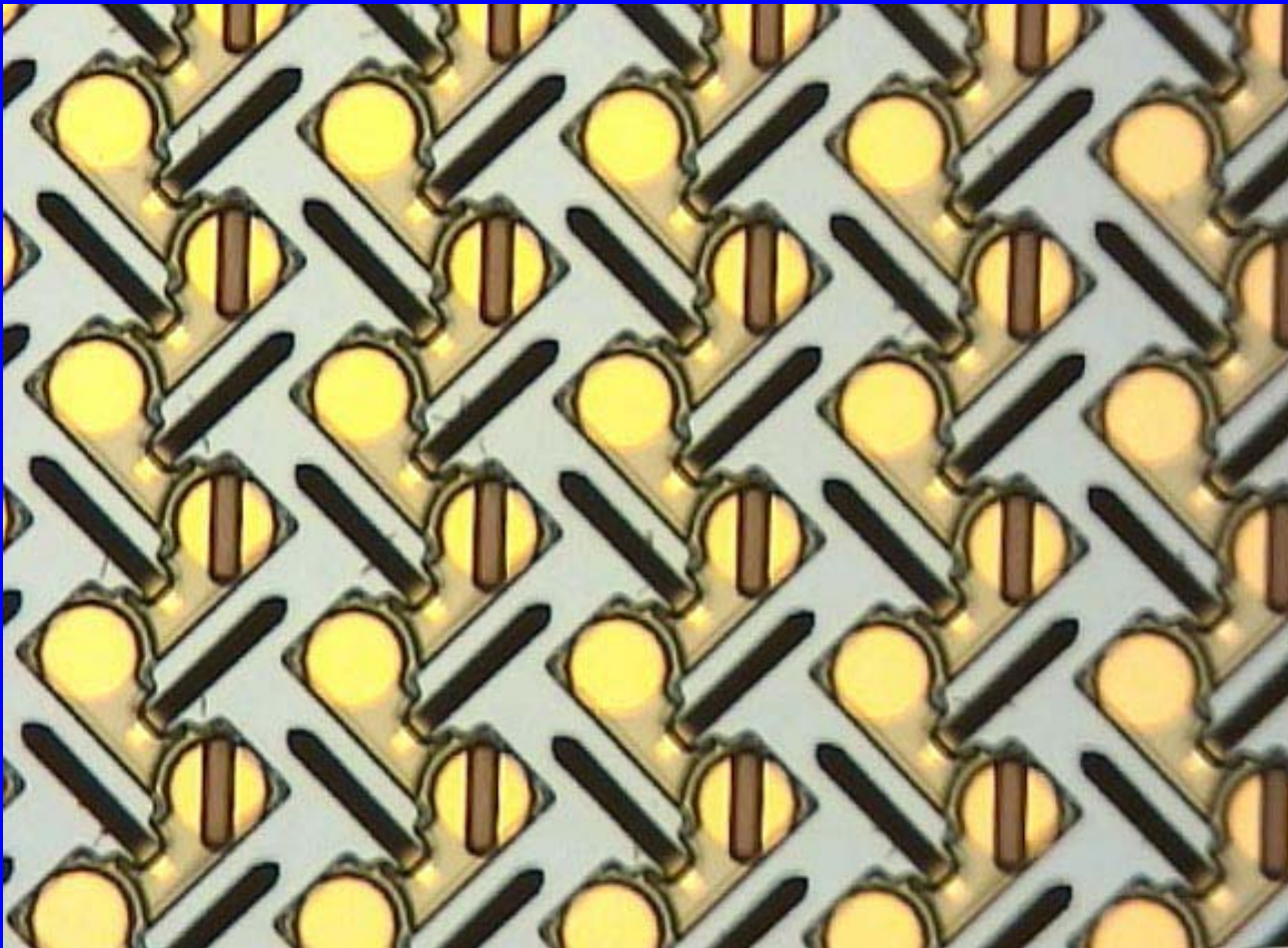
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Steps -- Full Wafer Test

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# Nano Spring Contactor



Contactor  
Array  
80 micron  
pads

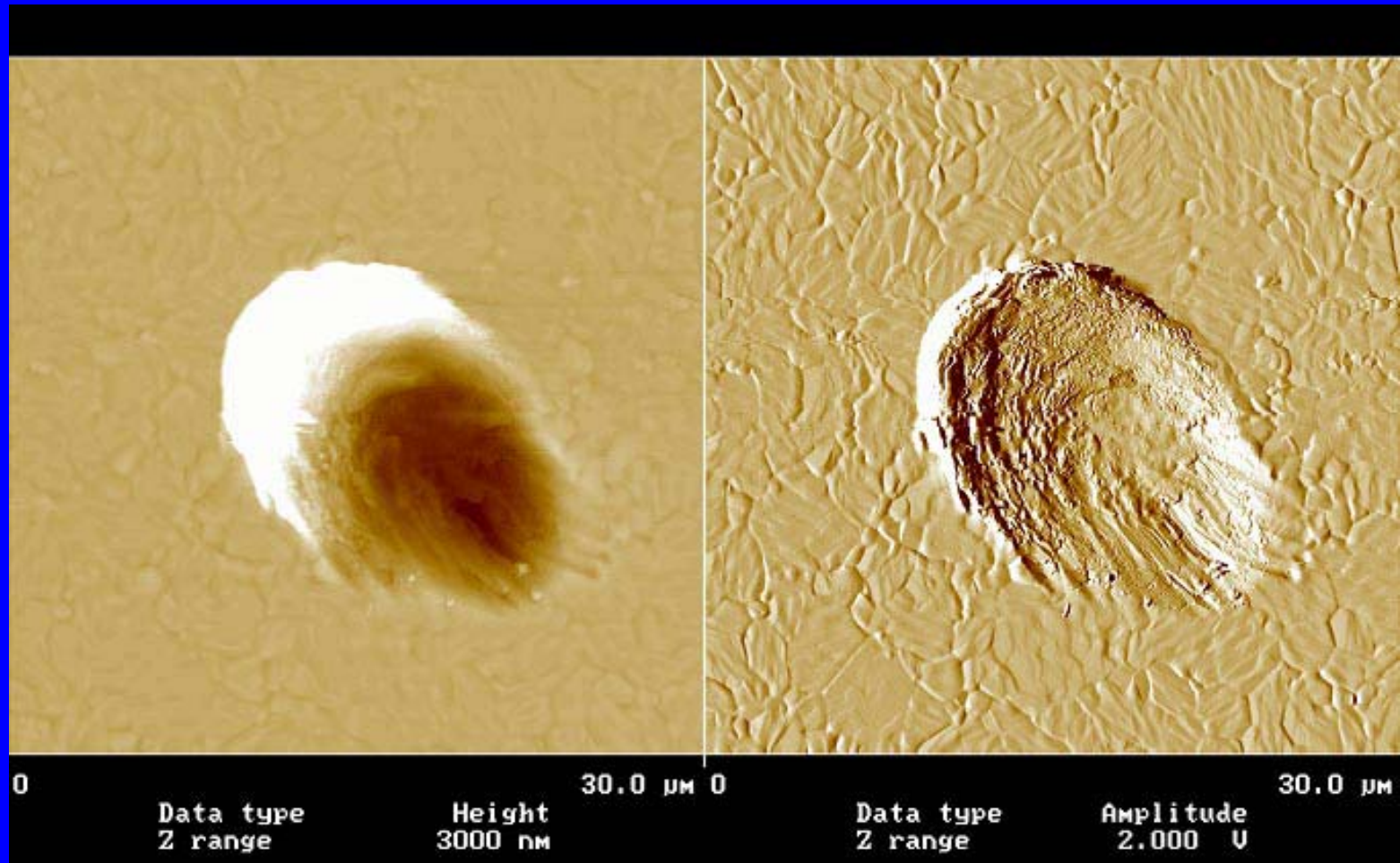
Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

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Steps -- Full Wafer Test

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# Probe Marks



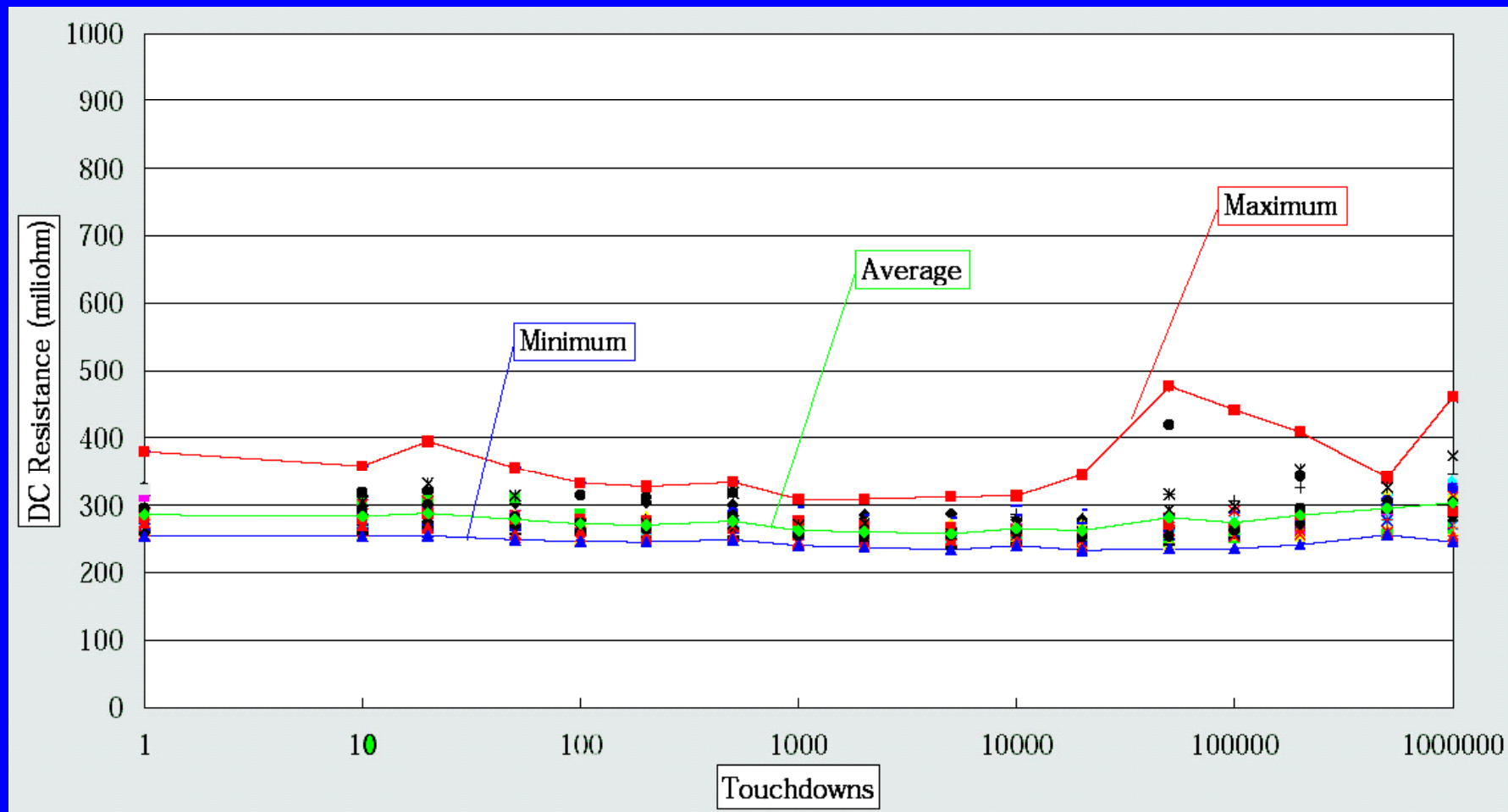
Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

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Steps -- Full Wafer Test

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# One Million Touchdowns



Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

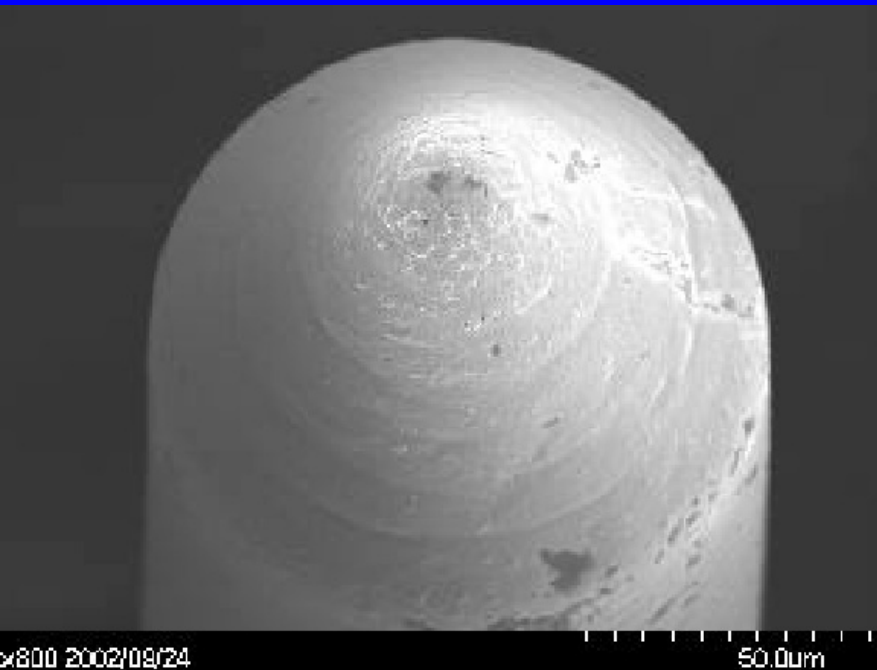
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Steps -- Full Wafer Test

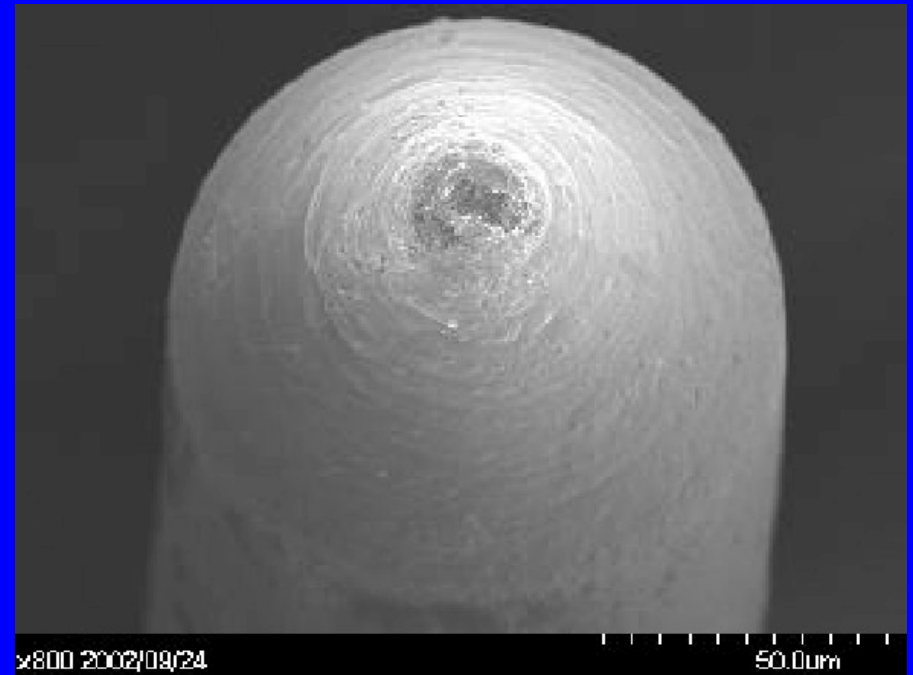
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# Micro Spring Before and After



Pin Tip before and



after 1 million touchdowns

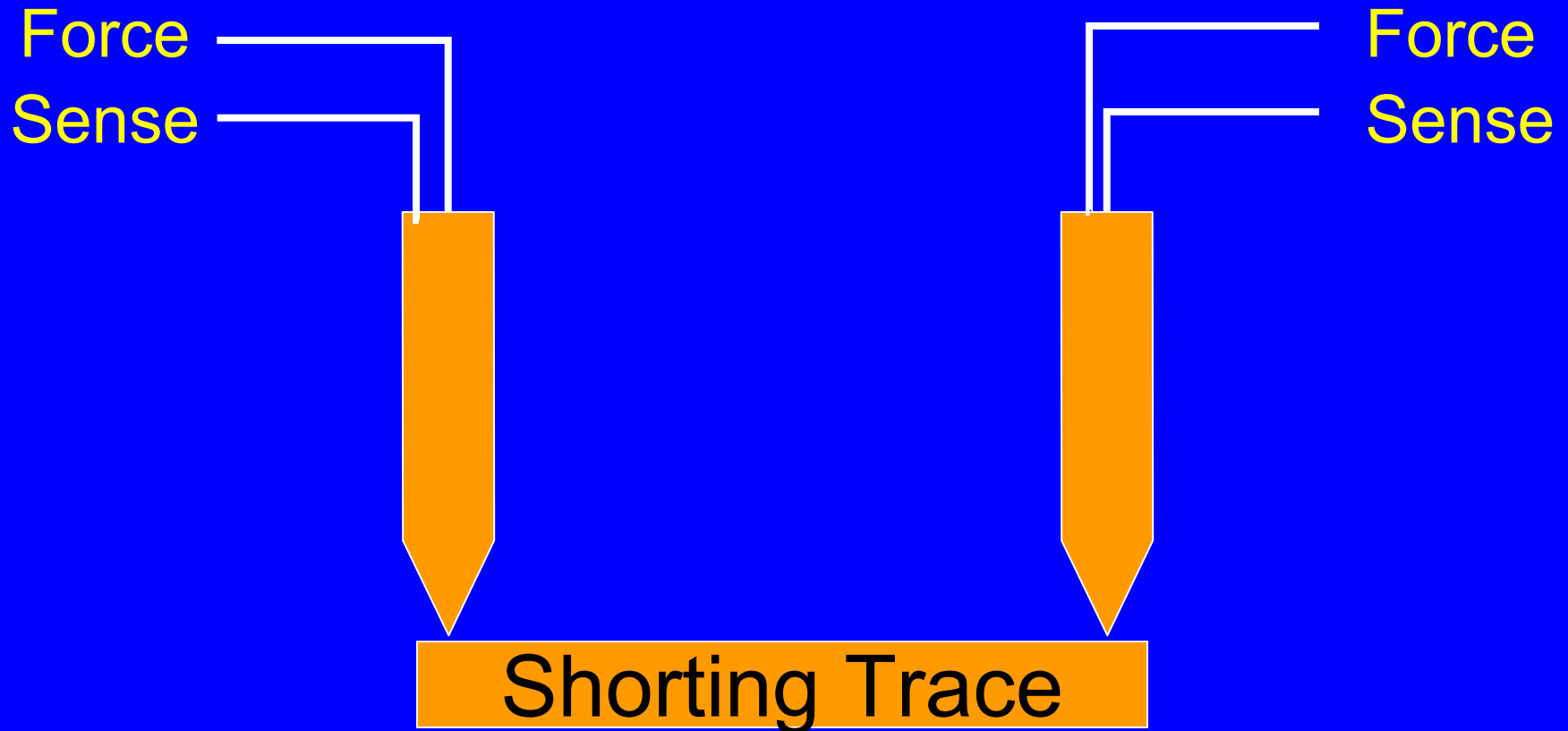
Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

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Steps -- Full Wafer Test

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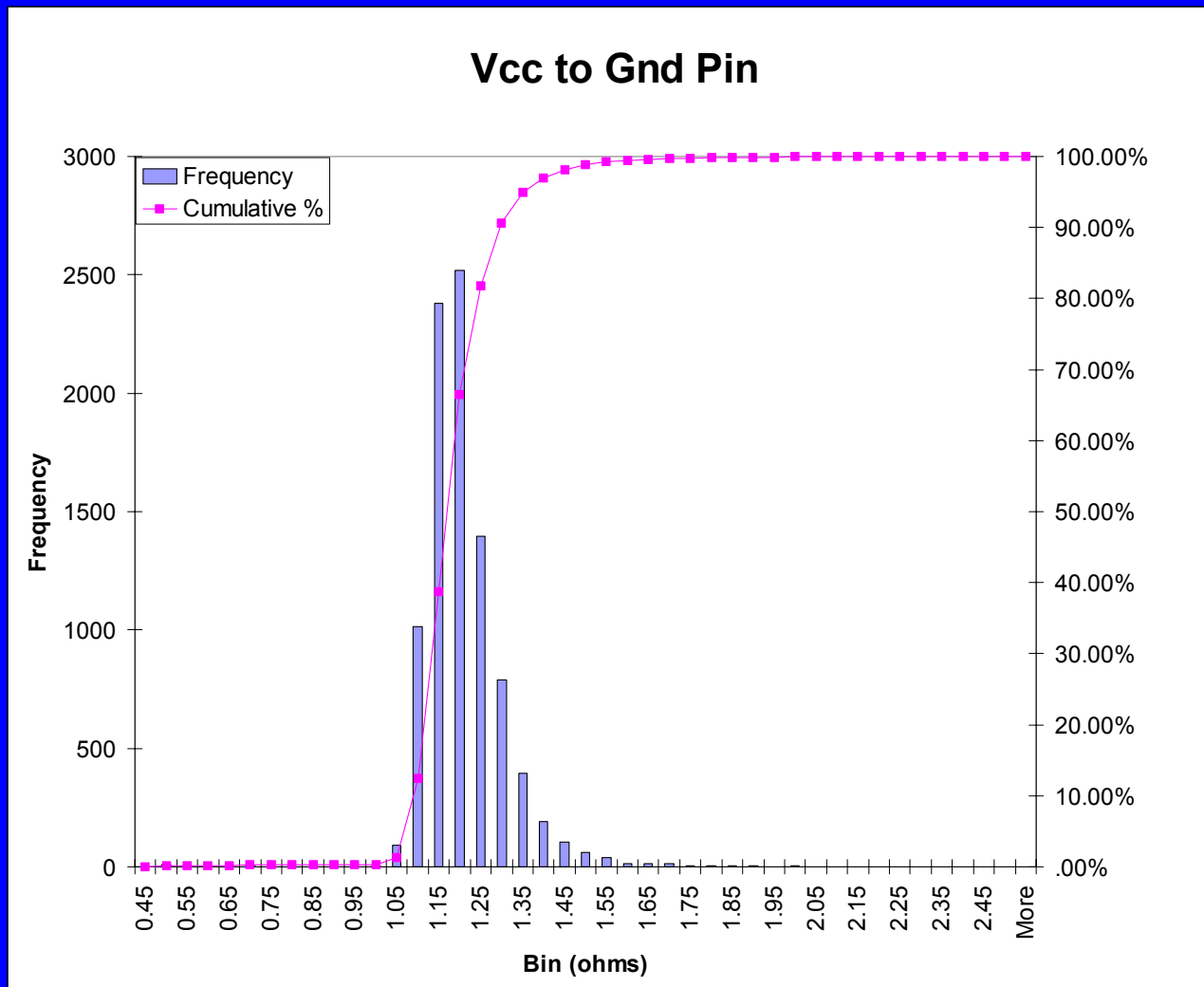
# Loop Resistance Diagram



Loop Resistance = Two contacts plus trace resistance

Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

# Loop Resistance Histogram



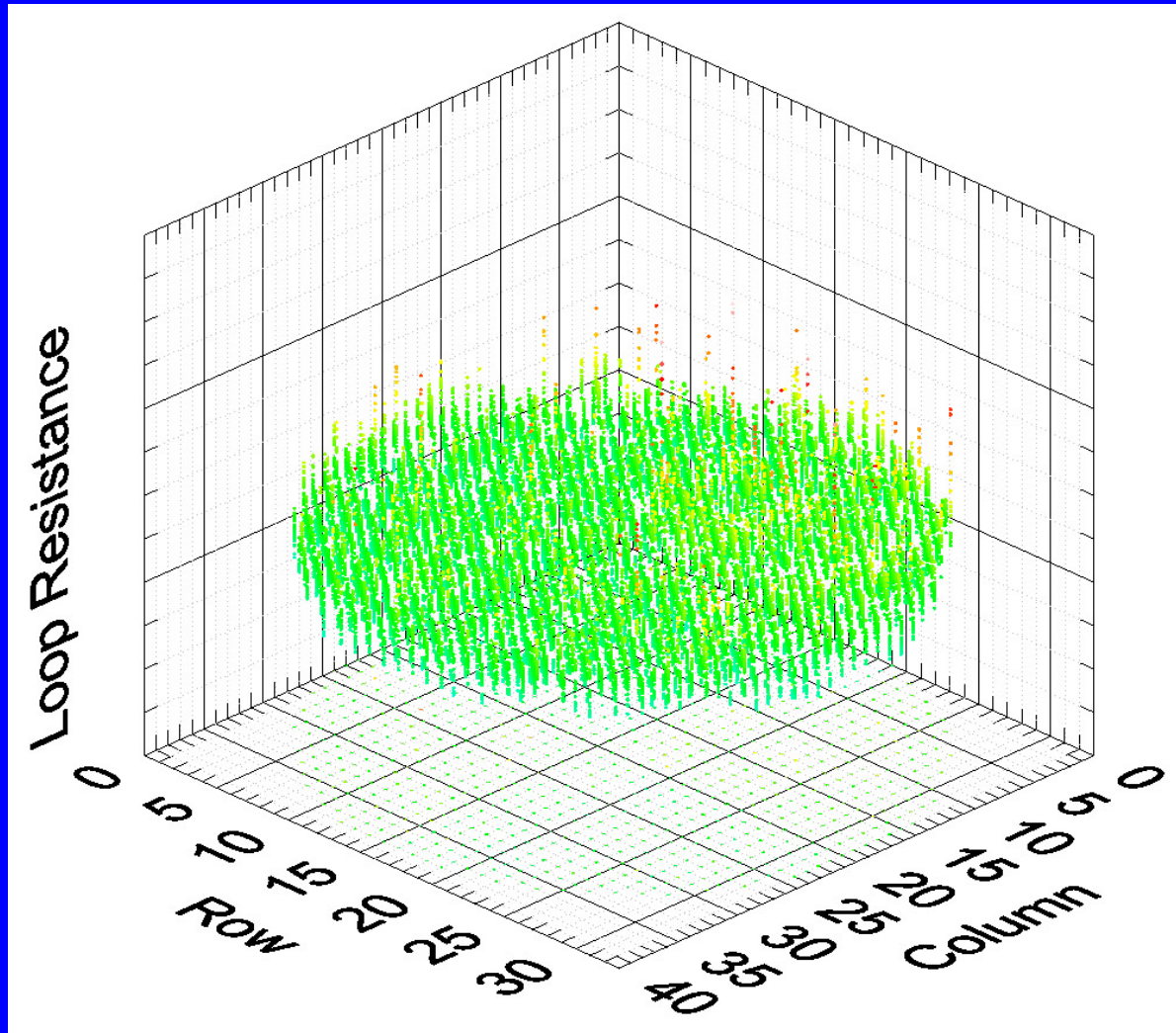
Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

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Steps -- Full Wafer Test

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# Full Wafer Contact Uniformity



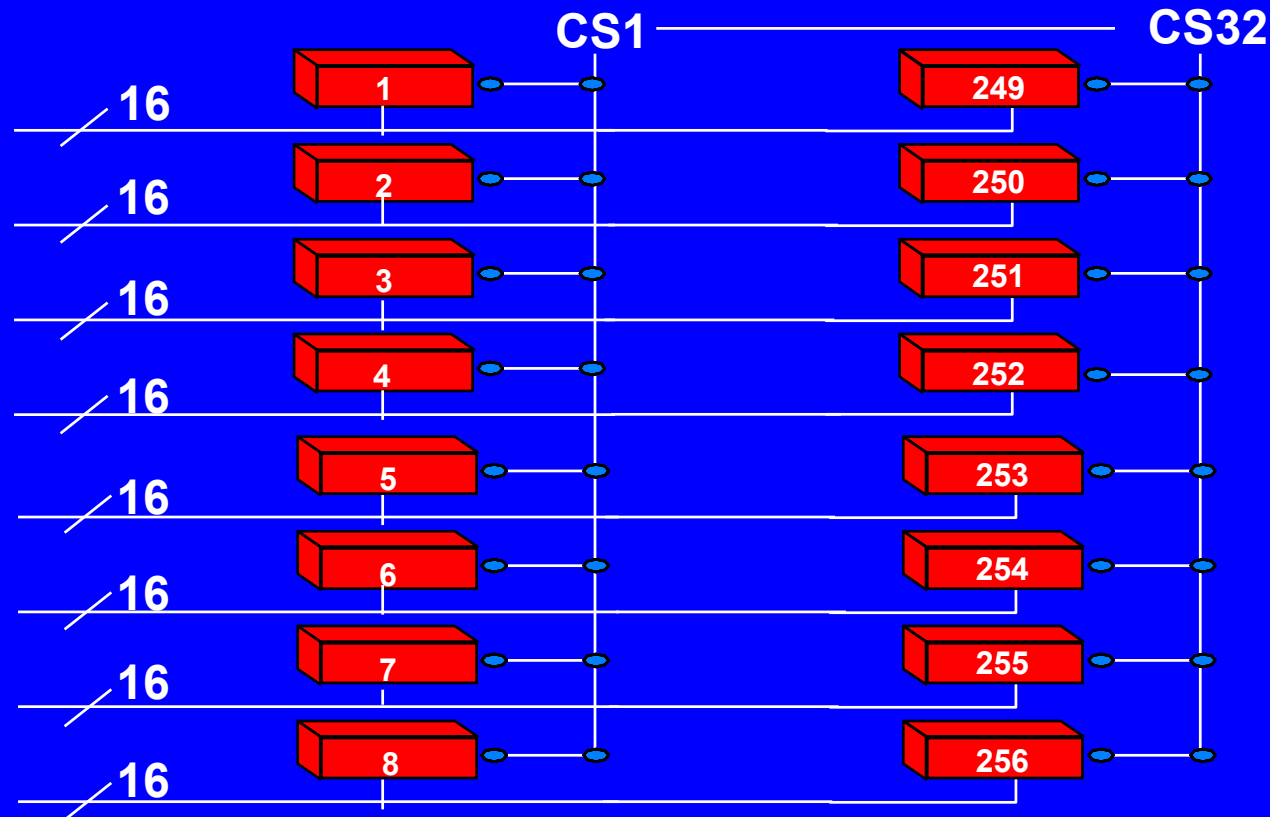
Source: Full Wafer Contact Reliability and Repeatability, Steps/Lindsey, SWTW 2003

# Massively Parallel Test

- **Massively Parallel testing spreads the channel cost across many device I/O pins**
  - **Parallel testing speeds are lower**
    - Capacitive loading reduces the maximum frequency
    - No need for ultra high speed channels
    - Cost per channel is lower
  - **Combination of:**
    - Multiple device I/O pins per channel
    - Lower per channel cost
- Much lower cost per device I/O pin**

# Parallel Testing

128 Tester I/O Channels X 32 CS = 4096 Total Device I/O Pins



Source: Full Wafer Contact Burn-In and Test -- The Ultimate in Parallelism?, Steps, BiTS 2003

# Standard Testing

- **Full I/O speed**
  - **Cost per channel very high (\$Ks/channel)**
  - **Signal cables must be very short**
  - **GHz testing very difficult**
- **Full I/O width**
  - **One channel per device pin**
  - **Total device count per test very limited**

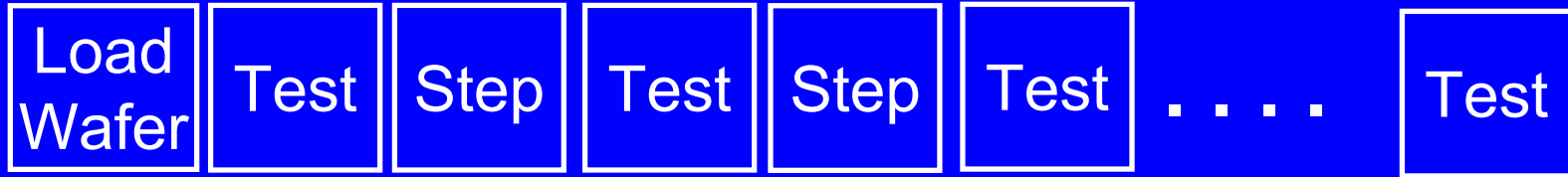
# Test Evolution – Structural Test

- Typically scan chain based
- External clock rate needed vastly reduced
- On chip ATPG
  - I/O width significantly reduced
  - Still can have edge timing constraints
- Design For Test (DFT)
  - Device I/O pin clock rate  $\ll$  Internal clock rate
  - Very narrow I/O (e.g., 5 pin IEEE 1149.1)
  - Channel cost reduced ( $< \$100/\text{channel}$ )
  - Parallel testing possible ( $< \$5/\text{device I/O}$ )



# Today's Testing Process

Using 32 site probe card:



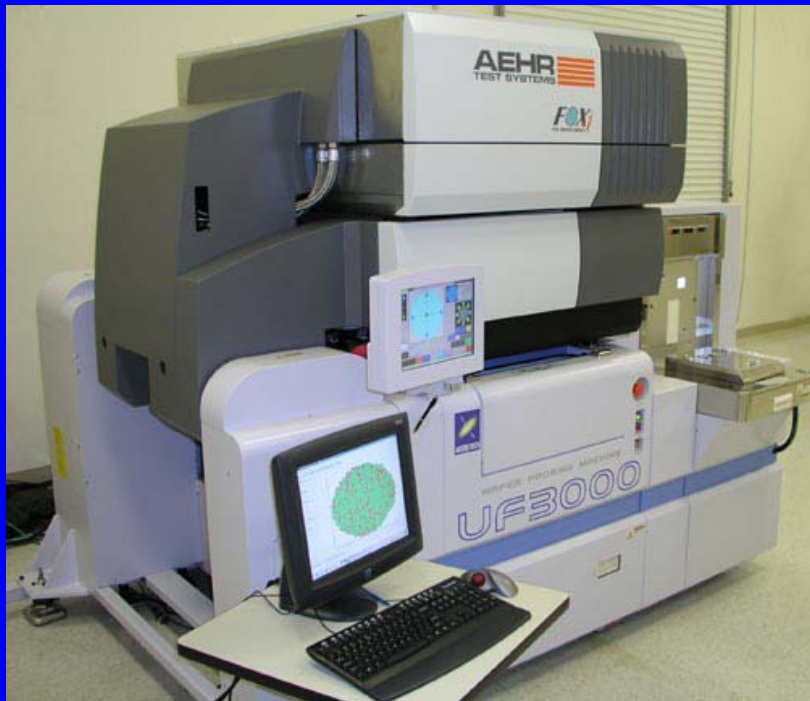
For 500 die wafer, about 20 cycles



# Full-wafer Approach



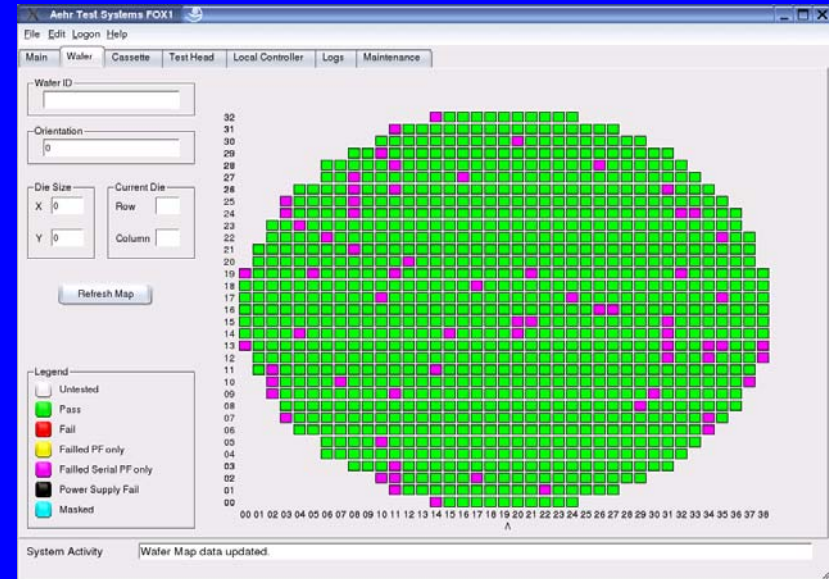
Only one cycle required



10-20X Time  
Reduction!

# Results of Technology Convergence

- **Correlation > 99% versus normal prober approach**
- **Massive reduction in:**
  - Total wafer test time
  - Product inventory on test floor
  - Capital equipment
  - Cost per tested die



# Conclusions

- Full wafer testing has arrived!

